

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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I.D.S.
1033 U.S. PTO
09/891693
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Applicants: Steve Biellak, Stanley E. Stokowski and Mehdi Vaez-Iravani
Assignee: KLA TENCOR TECHNOLOGIES CORPORATION
Title: SYSTEMS AND METHODS FOR A WAFER INSPECTION
SYSTEM USING MULTIPLE ANGLES AND MULTIPLE
WAVELENGTH ILLUMINATION
Serial No.: Unknown Filing Date: June 26, 2001
Examiner: Unknown Group Art Unit: Unknown
Docket No.: M-10693 US

San Francisco, California
June 26, 2001

BOX PATENT APPLICATION
COMMISSIONER FOR PATENTS
Washington, D. C. 20231

**INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR § 1.97(b)**

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, the documents listed on the accompanying PTO Form-1449 are called to the attention of the Examiner for the above patent application. Copies of these documents are enclosed.

Citation of these documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant invention;
2. a representation that a search has been made, other than as described above; or

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3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

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Respectfully submitted,



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